



Advances in Sensors and Electronic Instrumentation 2024

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submissions:

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Message from the Guest Editors

Dear Colleagues,

After successful events in 2015 (Dubai, UAE), 2016 (Barcelona, Spain), 2017 (Moscow, Russia), 2018 (Amsterdam, the Netherlands), 2019 (Tenerife (Canary Islands), Spain), 2020 (Porto, Portugal), 2021 (Palma de Mallorca (Balearic Islands), Spain), 2022 (Corfu, Greece), and 2023 (Funchal (Madeira Island), Portugal), the SEIA' 2024 will take place in Ibiza (Balearic Islands) on 25–27 September 2024 in co-location with the 6th IFSA Frequency and Time Conference (IFTC' 2024) and the 6th International Conference on Microelectronic Devices and Technologies (MicDAT '2024) under the same conference umbrella in-person format.

This Special Issue contains extended papers from SEIA' 2024 (<https://seia-conference.com/>) and MicDAT '2024 (<https://www.micdat-conference.com/>).

In addition, submissions from others that are not associated with these two conferences but with themes focusing on sensors and electronic instrumentation are also welcome.





Editor-in-Chief

Message from the Editor-in-Chief

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